


A GUIDE TO CRYOGENIC APPLICATIONS OF SIPMS

- Relatively young field
 - One running experiment (GERDA, LAr veto shield)
 - One experiment under commissioning (MEG II)
 - Few experiments in the preparation phase (DUNE, DarkSide, nEXO,...)
- Liquid Noble Gases experiment, new requirements and emphasis (very large area detectors, radiopurity, VUV sensitivity, low noise electronics and massive ganging, infrared sensitivity?? ..)
- Not much to standardize, yet, but rather share experience and guide the developments

MENU

- Review of the existing/planned experiments (Fabrice Retiere)
- Physics of SiPMs at cryogenic temperatures (Gianmaria Collazuol)
- Review of the readout electronics approaches (Wataru Ootani)
- Testing setups at cryogenic temperatures (Andrii Nagai)
- Reliability issues for large scale applications (Vishnu Zutshi)
- Interesting new contributions



PHYSICS OF SIPMS AT CRYOGENIC TEMPERATURES

AND IMPLICATIONS FOR THEIR PERFORMANCE AND CHARACTERISTICS

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A.Para, Fermilab

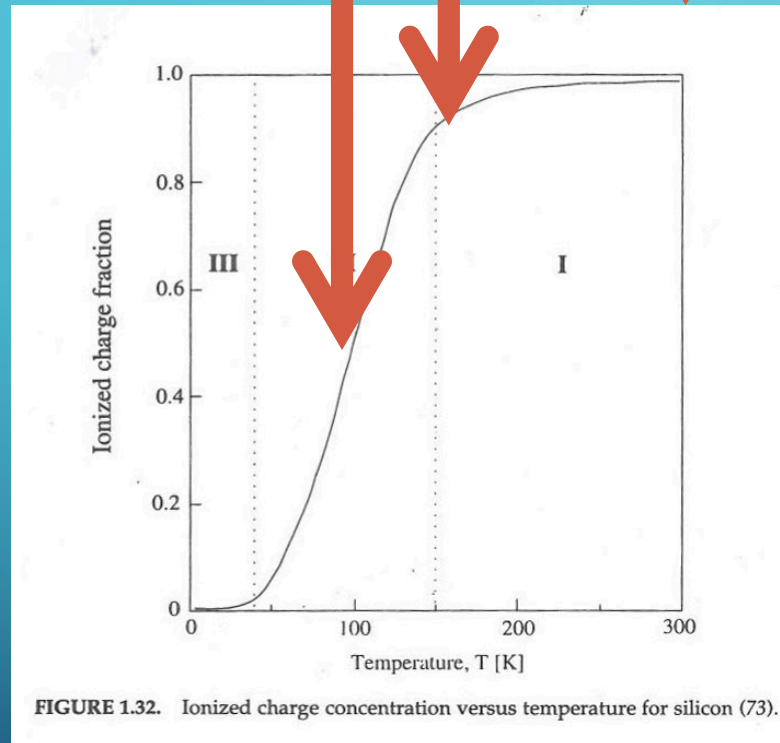
ICASiPM 2018, Schwetzingen

SUMMARY

- Cryogenic experiments (LXe/LAR) use SiPMs in the regime where the fundamental physics of silicon changes considerably (source of the figures: Gutierrez, Dean, Claeys “Low Temperature Electronics: Physics, Devices, Circuits and Applications”)
- (Some) SiPMs characteristics may vary significantly from room temperature to the operating conditions
- Cold/warm temperature variation may depend on the specific device design (room for the device optimization)

FREE CARRIERS IN DOPED SILICON

LAr LXe Room
temperature



Donors/acceptors levels
filled up. Insulator.

Donors/acceptors fully ionized by **thermal excitations**. Silicon is a semiconductor.

Free carriers produced by a temperature-dependent combination of

- Thermal excitations
- 'field-assisted' excitations
- tunneling

SILICON PROPERTIES AT LOW T: HIGHER CARRIER MOBILITY

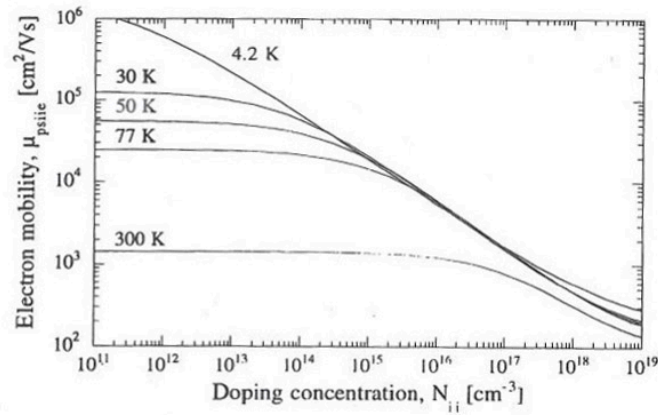


FIGURE 1.16. Calculated electron mobility due to phonon and ionized impurity scattering mechanisms. The five plots correspond to $T = 300, 77, 50, 30$, and 4.2 K.

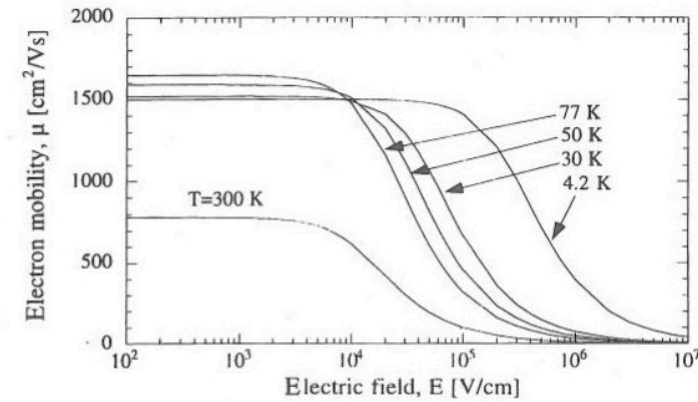


FIGURE 1.17. Calculated electron mobility, due to phonon, ionized impurities, and velocity saturation effects, as a function of the electric field for five temperatures; $N_{ii} = 10^{17} \text{ cm}^{-3}$.

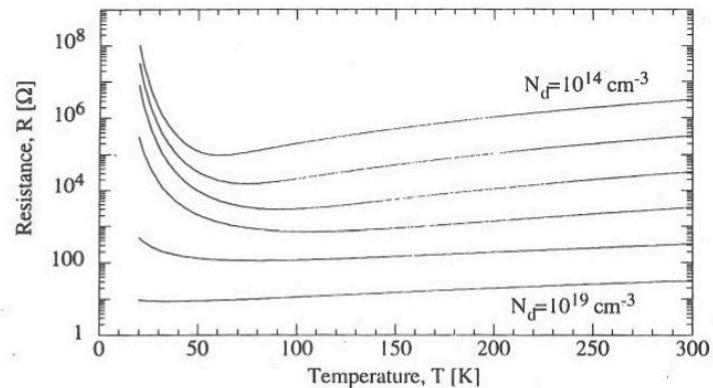
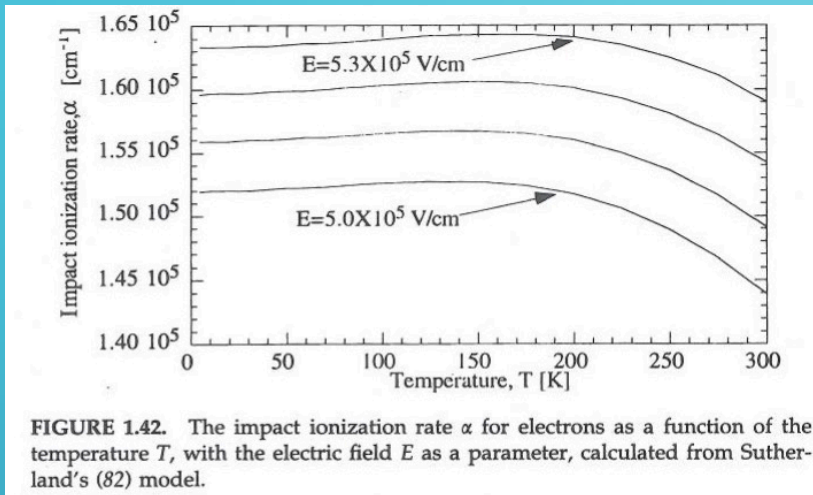


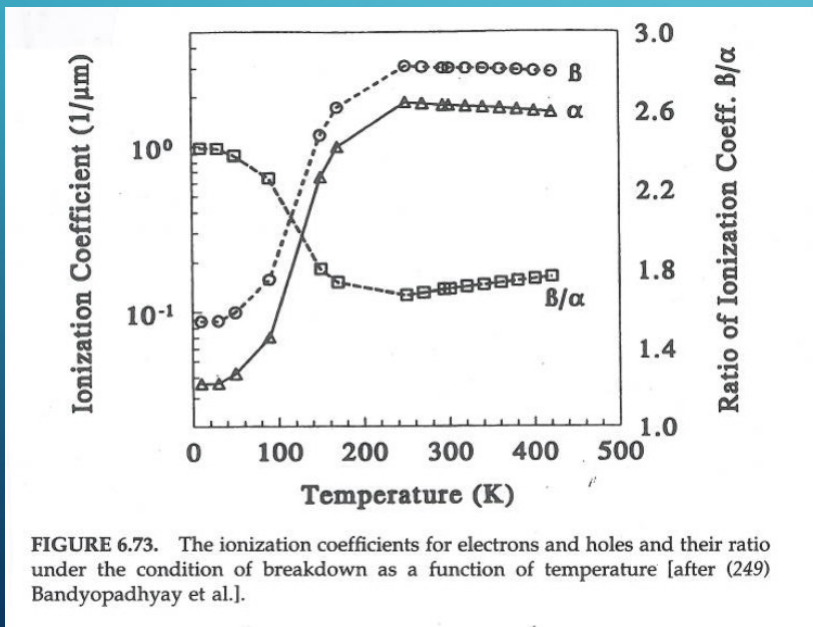
FIGURE 1.14. Calculated electrical resistance of a silicon slab of $(W/L) = 20/50 \text{ μm}$ and depth of 1 μm for different doping concentration levels.

- Carrier mobility → avalanche development, time development
- Temperature variation depends on doping profiles and electric fields → effect on SiPM performance may depend on the details of the SiPM design

SILICON PROPERTIES AT LOW T: IONIZATION COEFFICIENTS



- Impact ionization coefficient → avalanche development, time development, breakdown voltage
- Electron/hole variation → Wavelength dependence of PDE
- Temperature variation depends on doping profiles and electric fields → effect on SiPM performance may depend on the details of the SiPM design



AVALANCHE BREAKDOWN: TEMPERATURE VARIATION

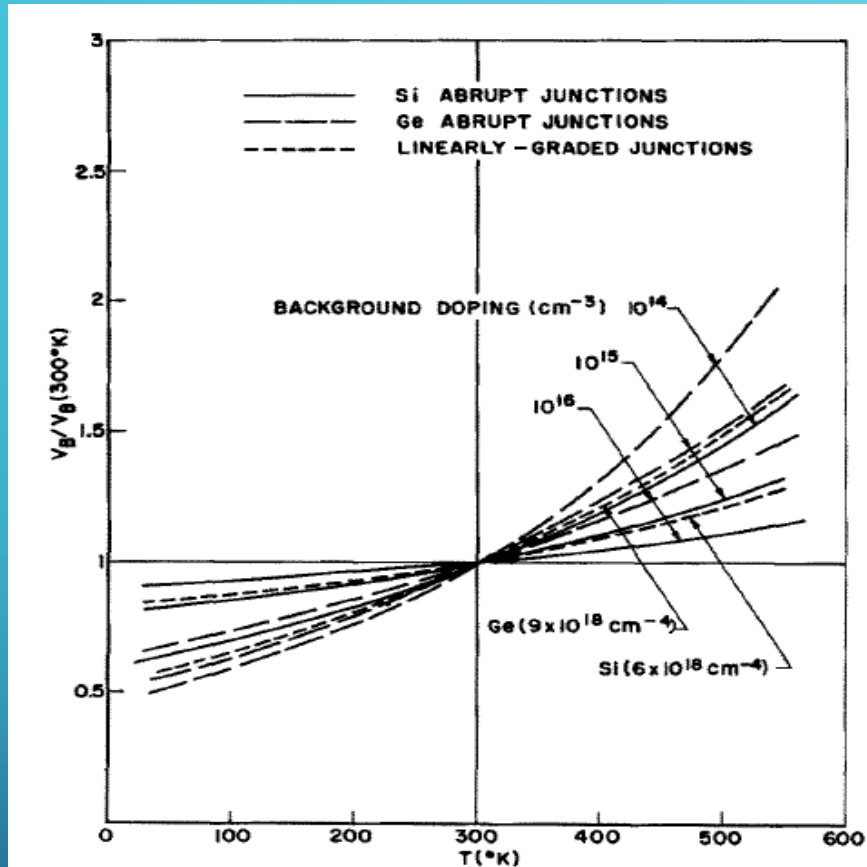


Fig. 4. Breakdown voltage vs temperature for Si and Ge p - n junctions. $V_B(300^\circ\text{K})$ is 2000, 330, and 60 V for Si and 950, 150, and 25 V for Ge for dopings of 10^{14} , 10^{15} , and 10^{16} cm^{-3} respectively. The linear-graded junctions have $V_B(300^\circ\text{K})$ the same as those for doping of 10^{15} cm^{-3} .

Avalanche breakdown V is expected to show a **non linear dependence on T** (depending of the junction type and doping concentration)

Breakdown V decreasing with T due to increasing mobility

NOTE: in freeze-out regime Zener (tunnel) breakdown could be relevant.

→ negative Temperature coefficient (increasing with decreasing T)

Crowell and Sze

More recent model by Crowell and Okuto after Shockley, Wolff, Baraff, Sze and Ridley.

SILICON ABSORPTION LENGTH AT LOW TEMPERATURES

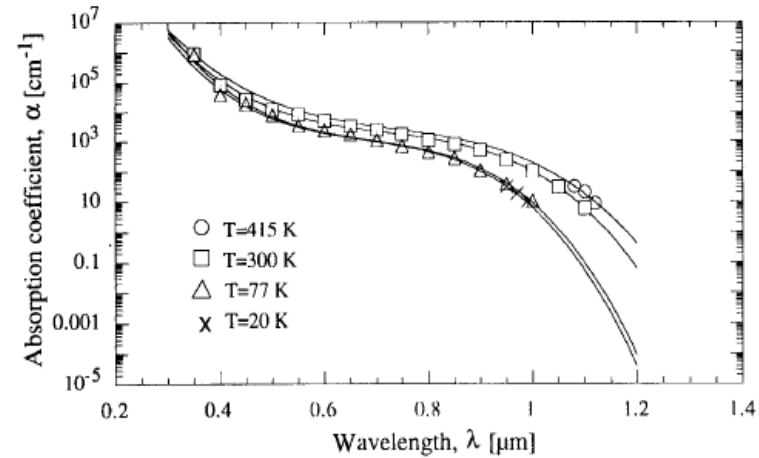


FIGURE 1.53. Experimental (symbols) and fitted (lines) absorption coefficient α of silicon at $T = 415, 300, 77$, and 20 K [replotted from Rajkanan *et al.* (109)].

- Variation of the wavelength-dependence of PDE with temperature

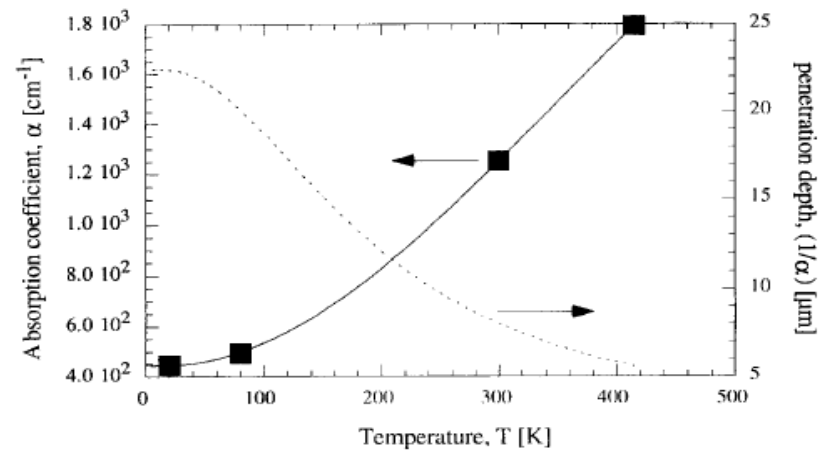
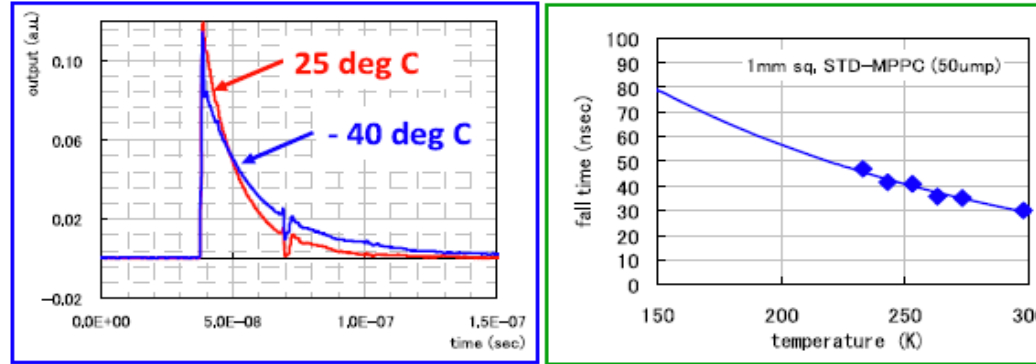


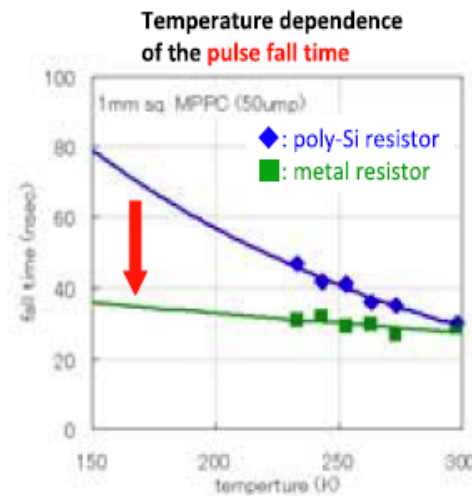
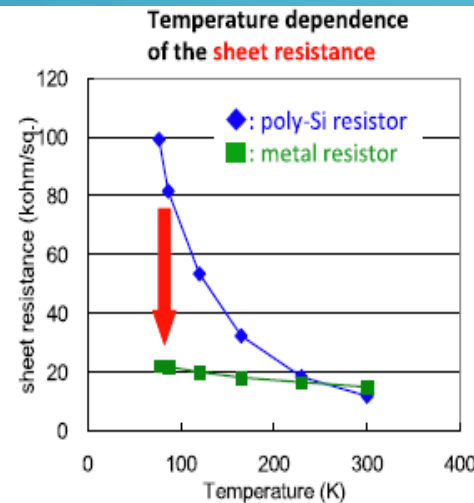
FIGURE 1.54. Measured absorption coefficient α (■) (101) and fitted α (solid line) versus temperature T . On the right axis the fitted penetration depth ($1/\alpha$) is also shown.

IN ADDITION: QUENCHING RESISTOR



The quenching resistor value increases as environmental temperature decreases. The larger resistor makes the pulse amplitude lower and the tail longer.

Adopting
metal
quenching
resistor



Metal quenching resistor achieved 1/5 temperature dependence

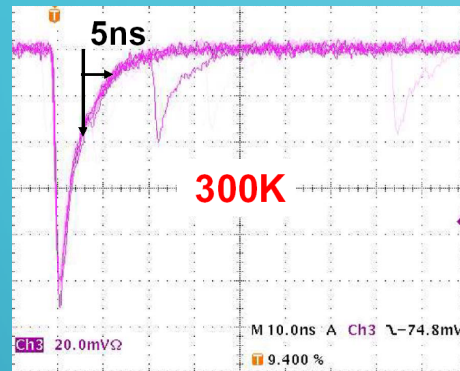
Improved
temperature
stability

PULSE SHAPE: DEPENDENCE ON TEMPERATURE

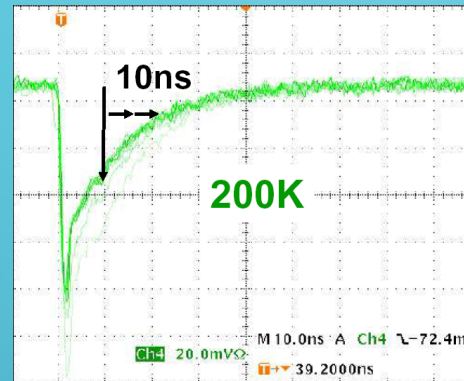
The two current components behave differently with Temperature

→ fast component is independent of T because C_{tot} couples to external R_{load}

→ slow component is dependent on T because $C_{d,q}$ couple to $R_q(T)$



HPK MPPC



H.Otono, et al. PD07

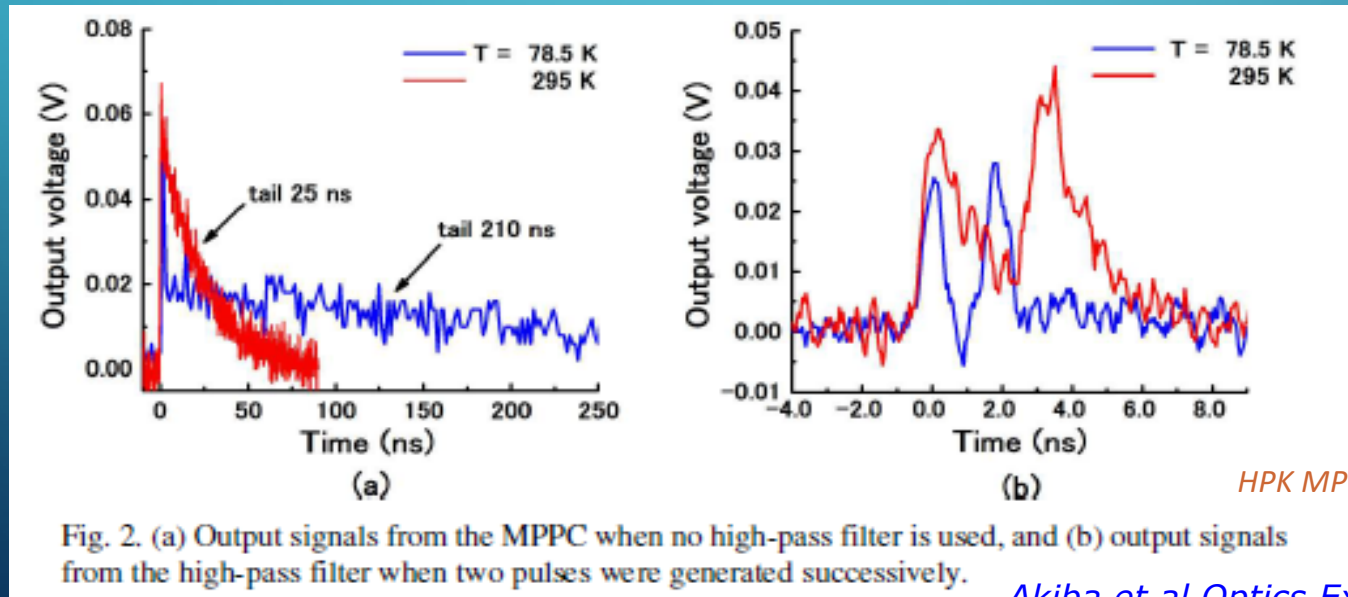
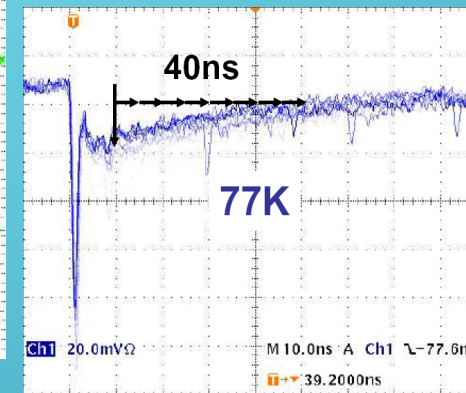
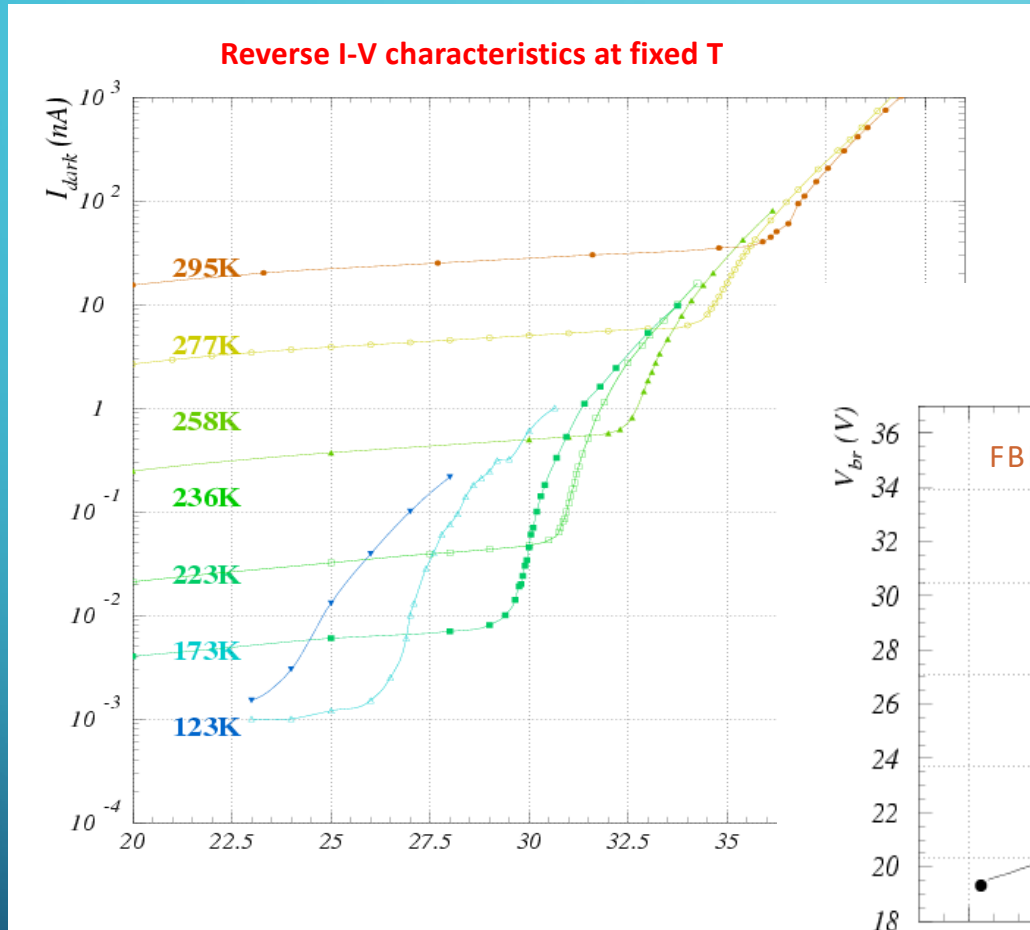


Fig. 2. (a) Output signals from the MPPC when no high-pass filter is used, and (b) output signals from the high-pass filter when two pulses were generated successively.

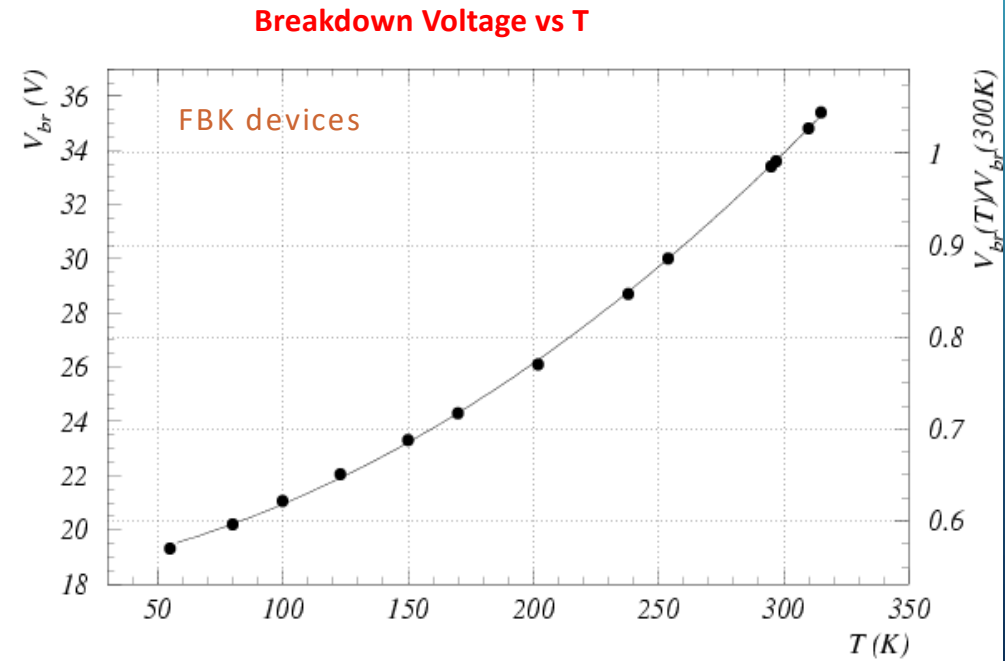
Akiba et al Optics Express 17 (2009) 16885

high pass filter / shaping
→ recover fast signals

REVERSE BIAS I-V CURVES → DARK CURRENT AND V_{BD}



Dark current decreases rapidly with T
at rate $\sim x2 / 10K$



Breakdown voltage decreases
at low T due to larger carriers mobility
→ larger ionization rate (electric E field fixed)

G.C. et al NIM A628 (2011) 389

V_{BD} VS $T \rightarrow$ TEMPERAURE COEFFICIENT (ΔV STABILITY)

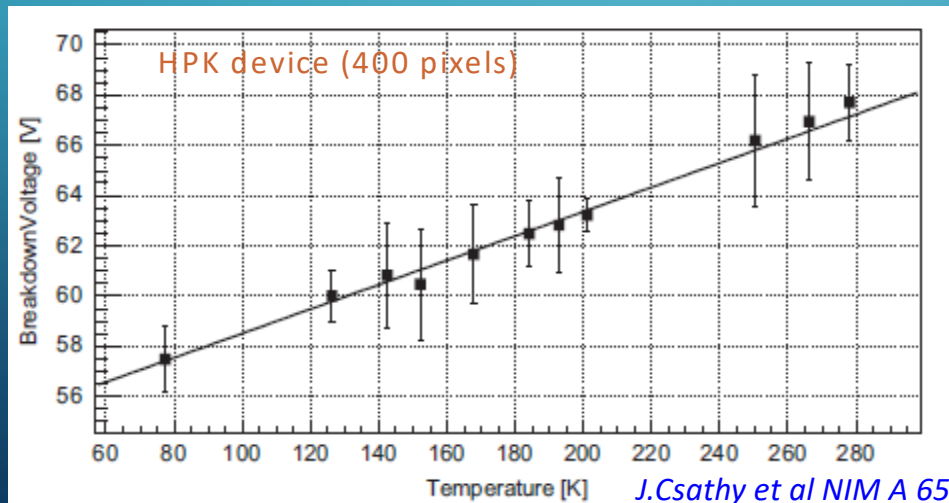
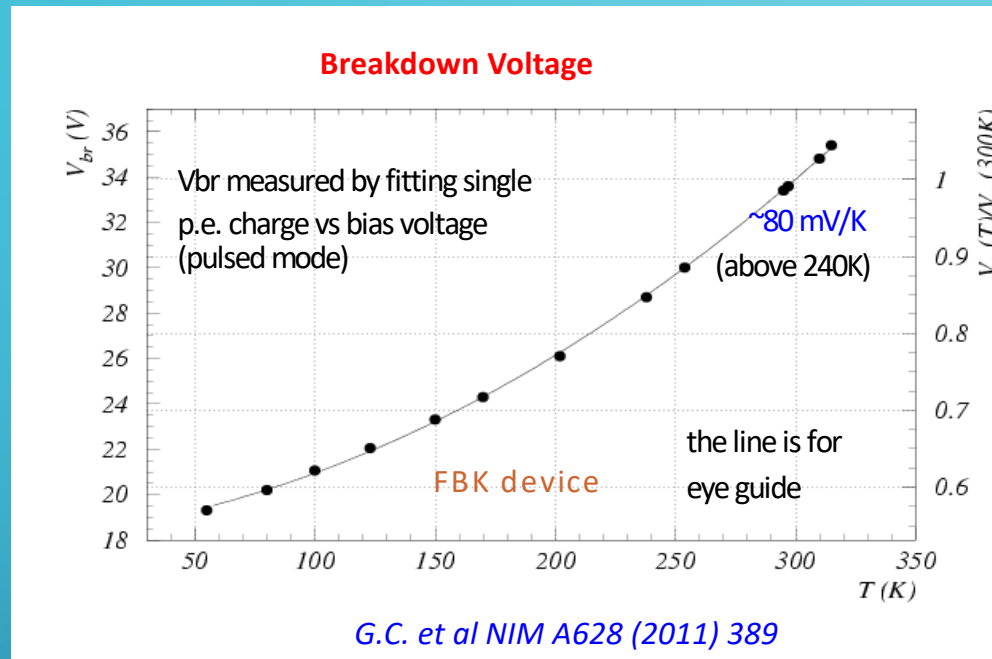
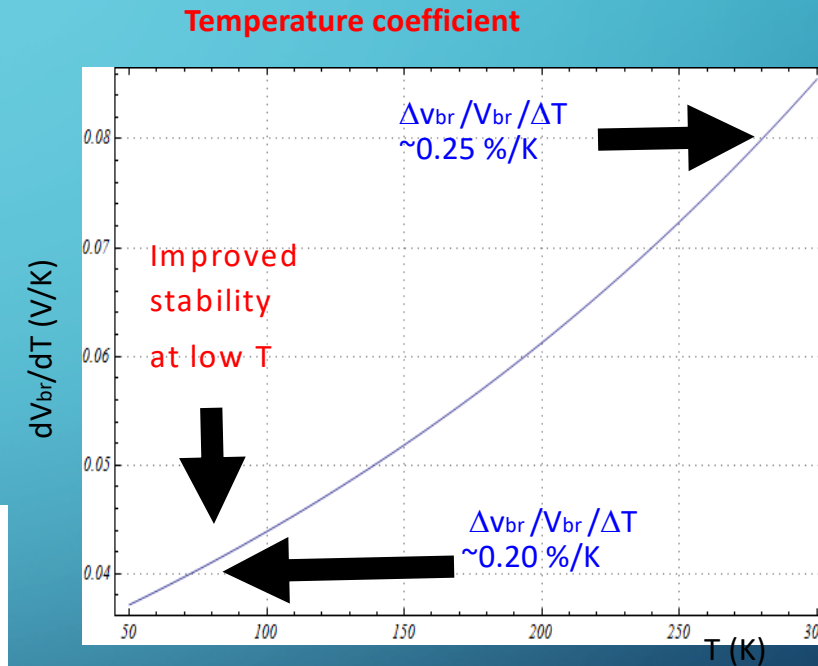


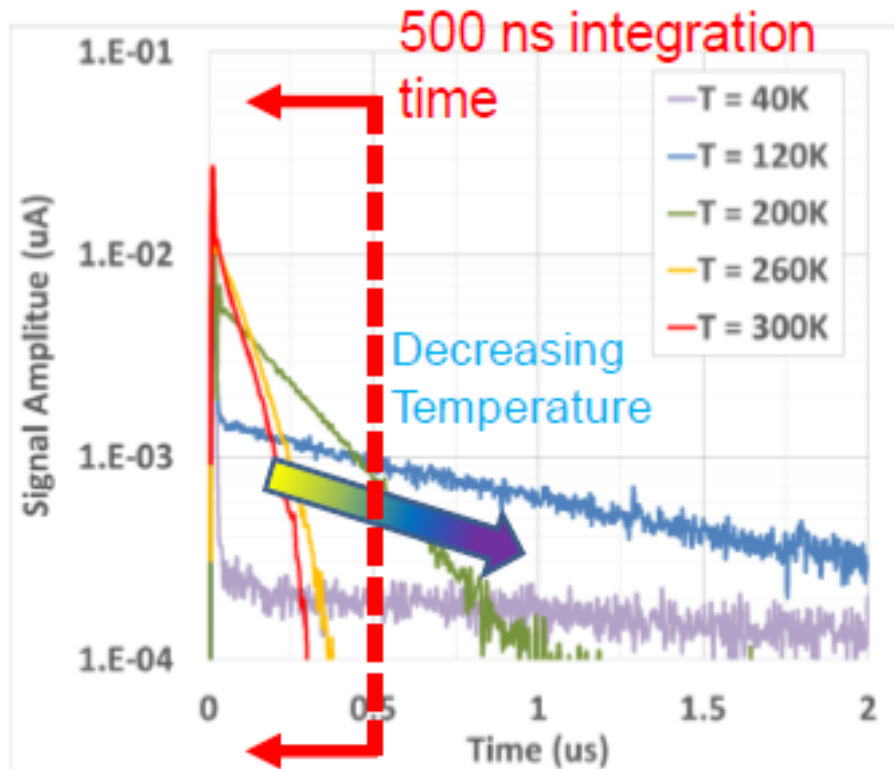
Fig. 6. Breakdown voltage as a function of temperature of the MPPC with 400 pixels.



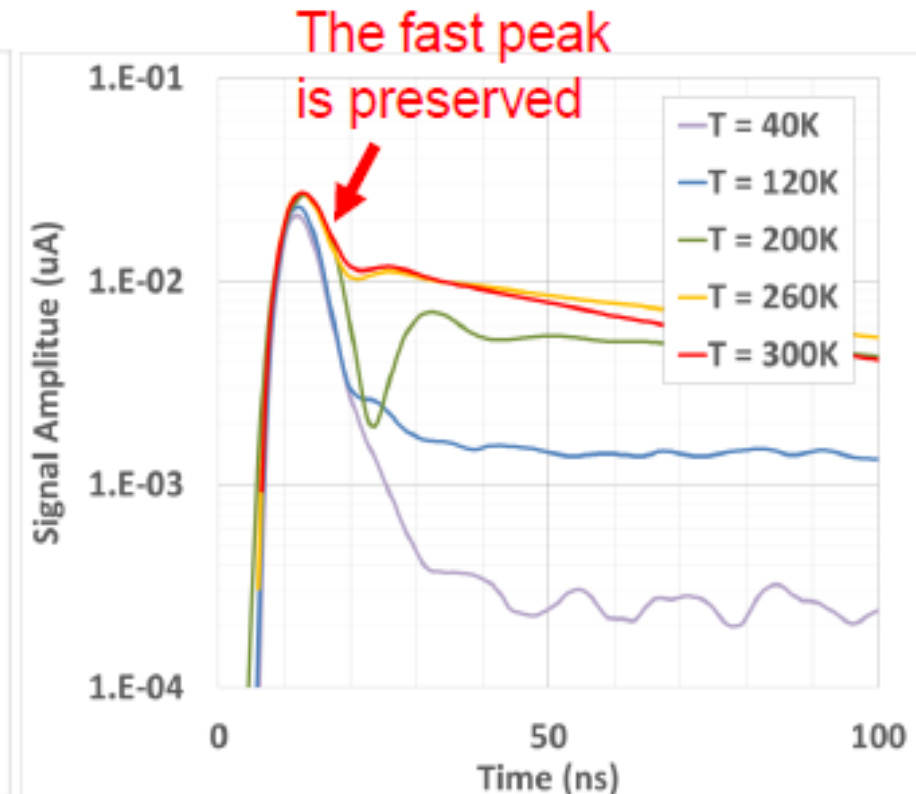
PULSE SHAPE VS T

Alberto Gola – IEEE NSS-MIC 2015

The exponential tail of the **single cell response (SCR)** becomes almost negligible at cryogenic temperature.



Average SCR

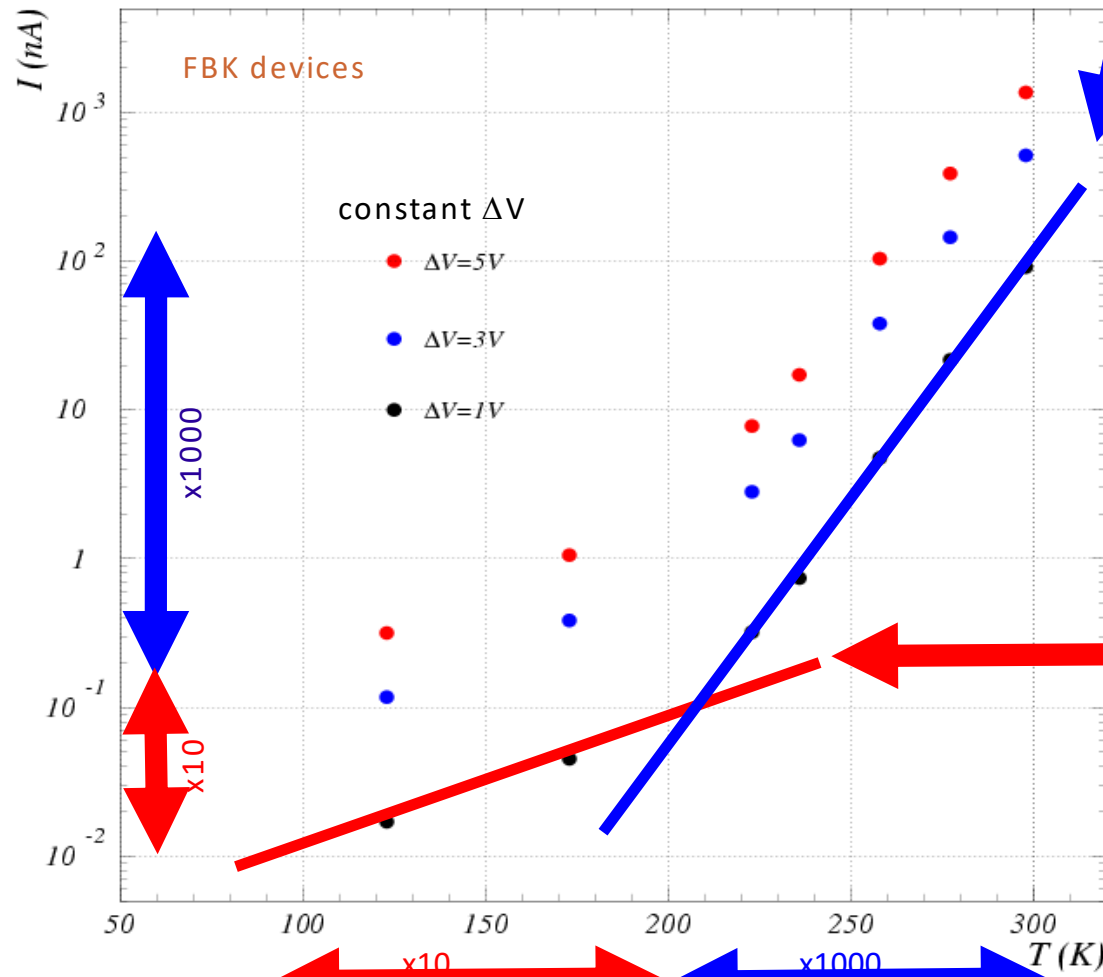


Zoom of the first part of the SCR

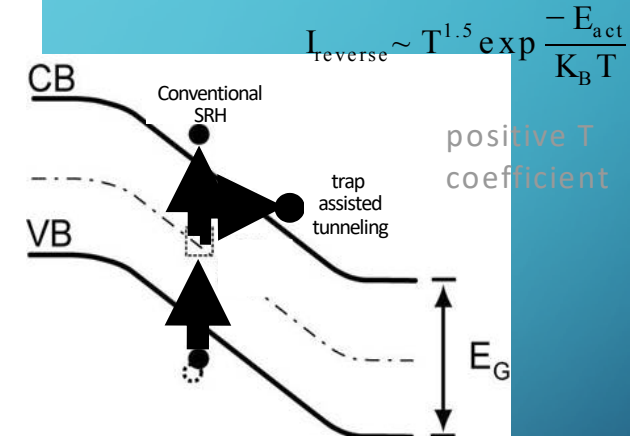
DARK CURRENT VS T sources of DCR

contribution to DCR
from diffusion of minority
carriers negligible below 350K

Noise mainly comes from the **high E Field region** (no
whole depletion region)

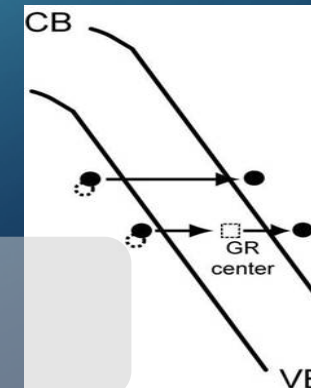


1) **Generation/Recombination SRH**
noise (enhanced by
trap assisted tunneling)



2) **Band-to-band Tunneling noise**
(strong dependence on the Electric
field profile)

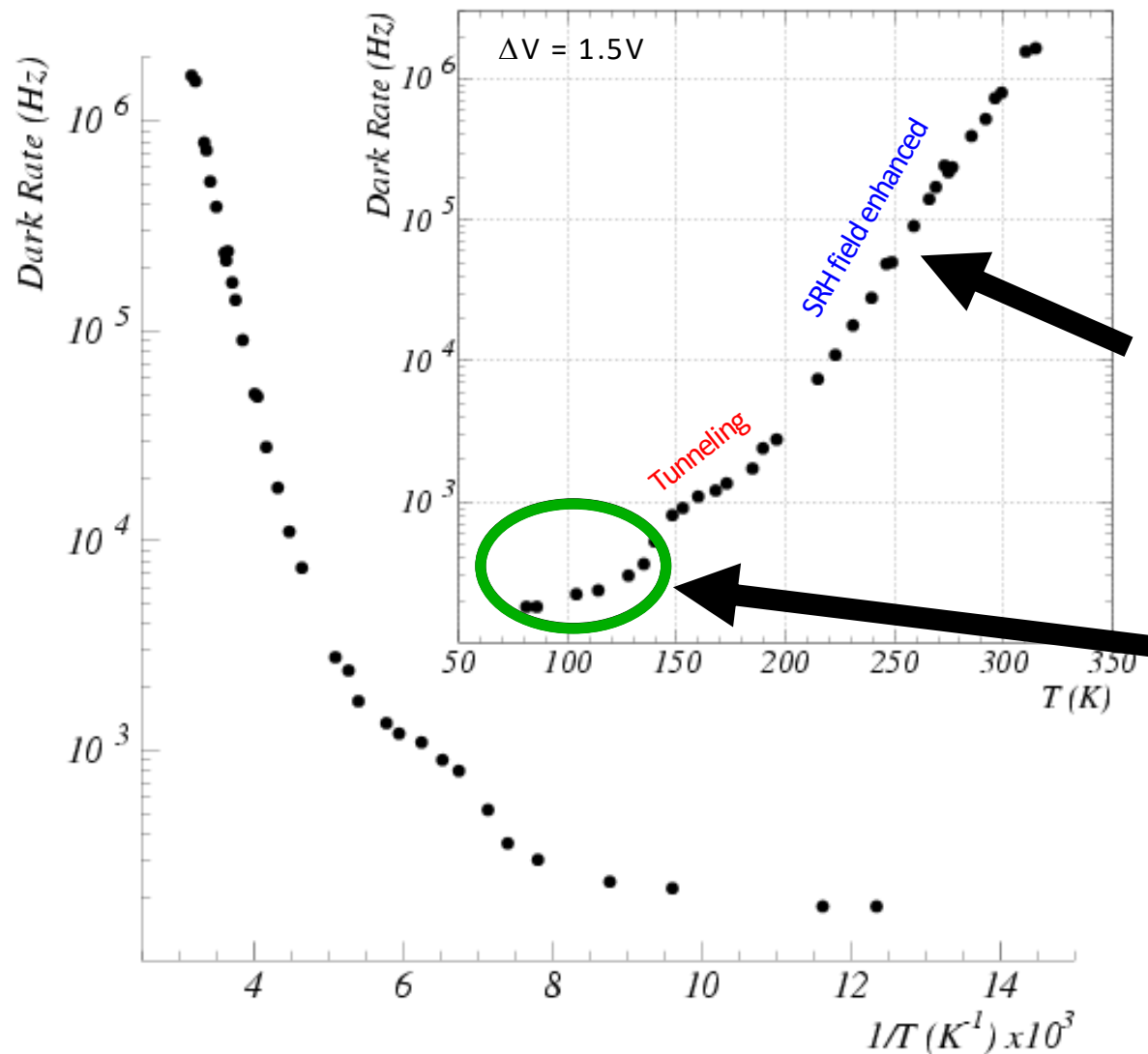
negative T
coefficient



Tunneling noise dominating for $T < 200K$
(sharp high E field region \rightarrow higher noise)

**E field engineering is
crucial for min. DCR
(esp. at low T)**

DARK COUNT RATE VS TEMPERATURE (CONSTANT ΔV)



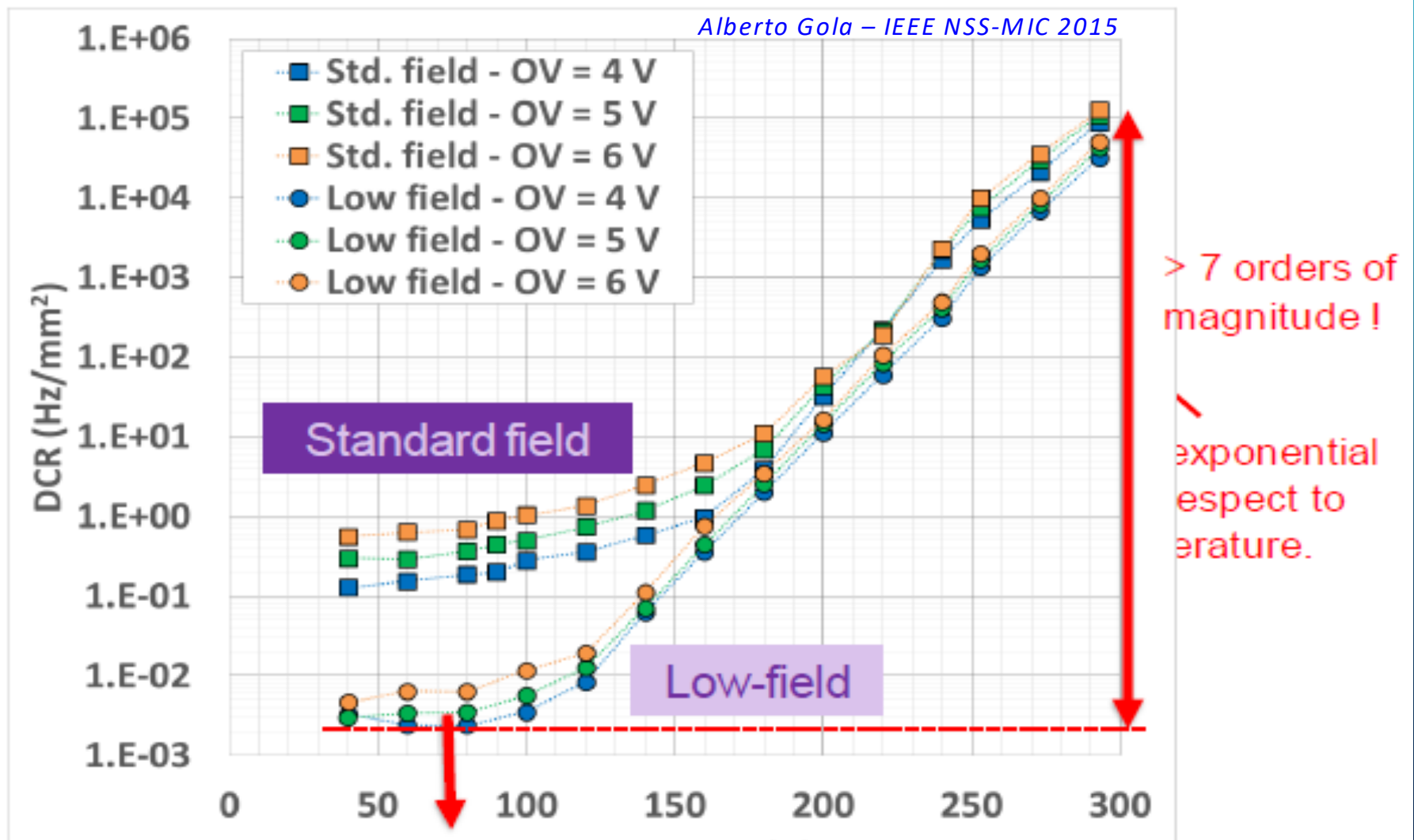
Measurement of
counting rate of ≥ 1 p.e.
at fixed $\Delta V = 1.5$ V
(\rightarrow constant gain)

$$\text{DCR} \sim T^{1.5} \exp \frac{-E_{\text{act}}}{K_B T}$$

Activation energy $E_{\text{act}} \sim 0.36$ eV

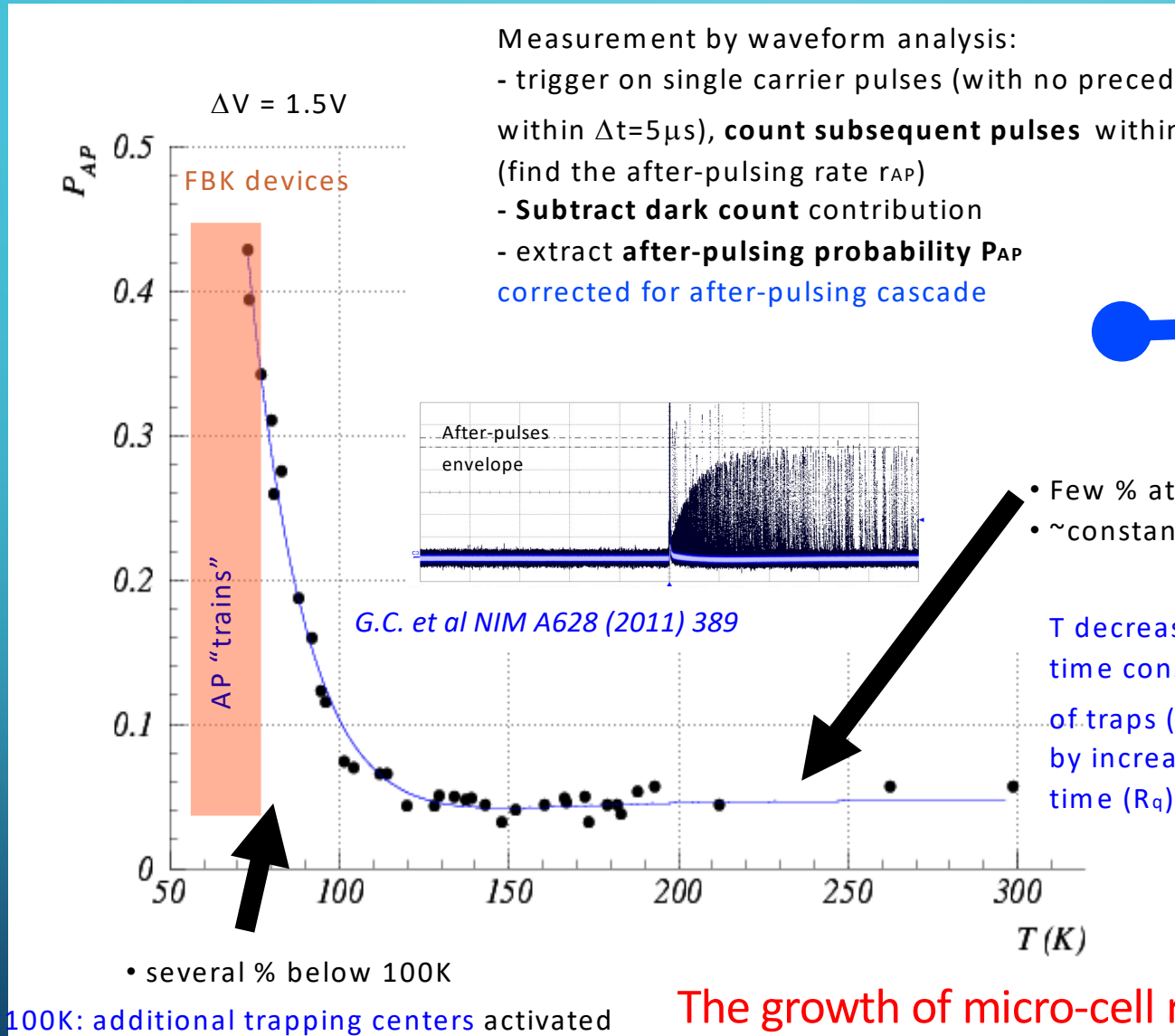
??? onset of carriers freeze-out
(carrier losses at very low T
due to ionized impurities acting
as shallow traps)
Under investigation

OPTIMIZE SIPM FOR CRYOGENIC OPERATION: FBK



A 10x10 cm² SiPM array would have a total DCR < 100 Hz!

AFTER-PULSES VS T (CONSTANT DV)



$$P_{AP} = \frac{r_{AP}}{1 + r_{AP}}$$

- Few % at room T
- ~constant down to ~120K

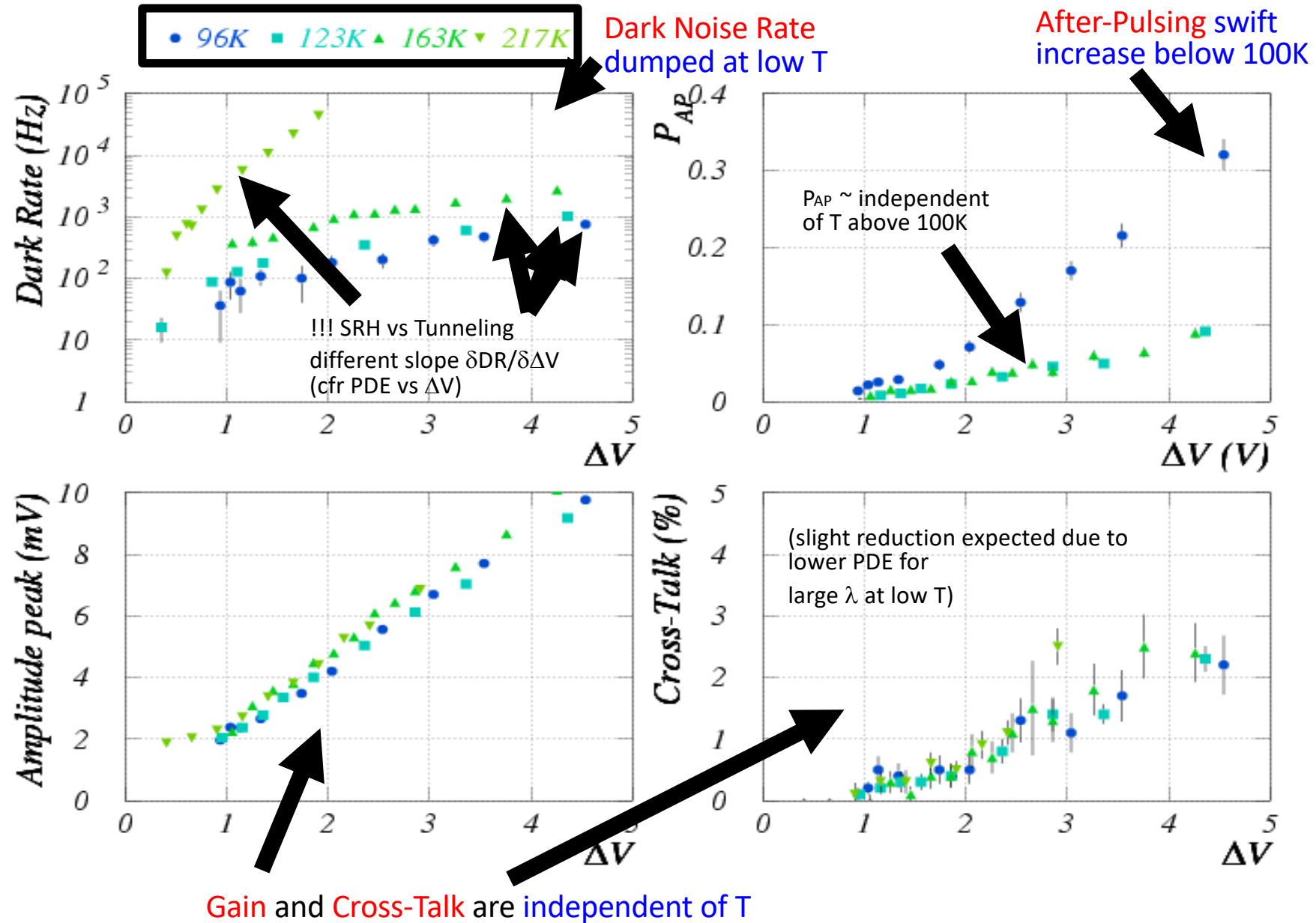
T decreasing: increase of characteristic time constants of traps (τ_{traps}) compensated by increasing cell recovery time (R_q)

- several % below 100K

$T < 100K$: additional trapping centers activated possibly related to onset of carriers freeze-out

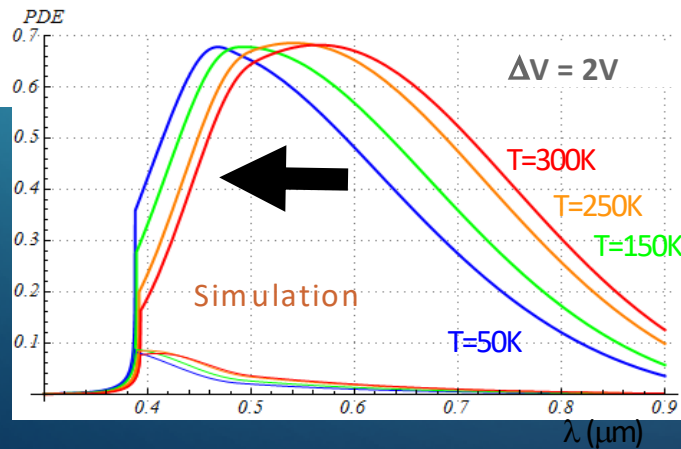
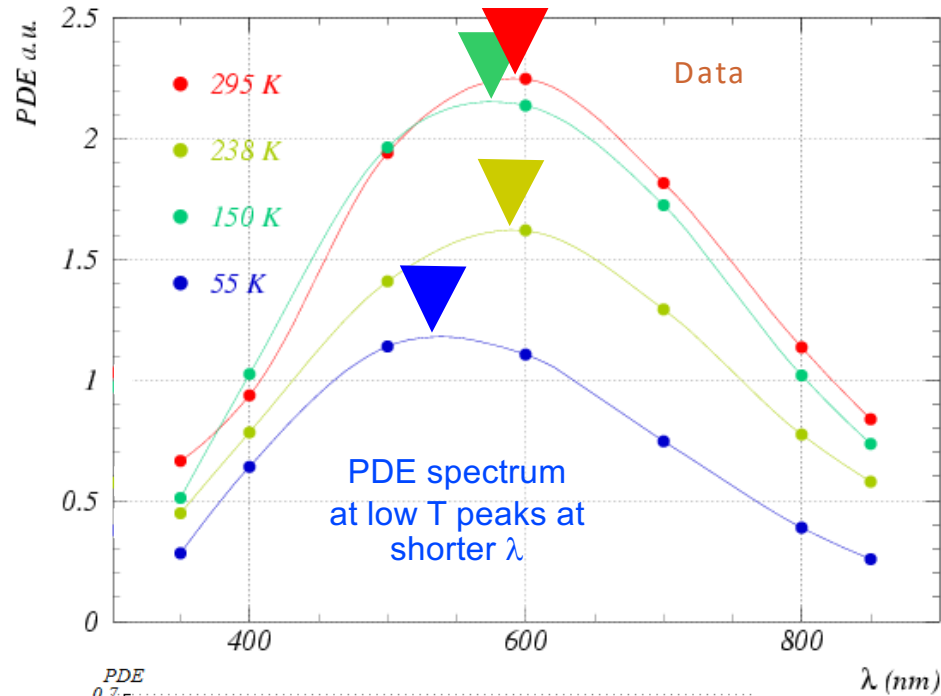
The growth of micro-cell recharge time help reducing the after-pulsing at low T

QUICK GUIDE: DARK RATE, AFTERPULSES, CROSS TALK

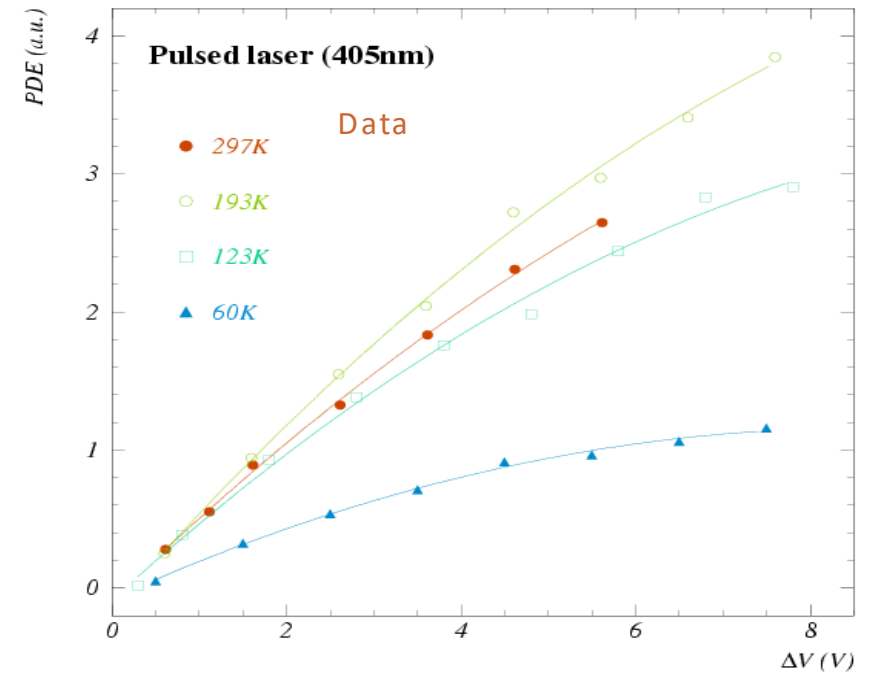
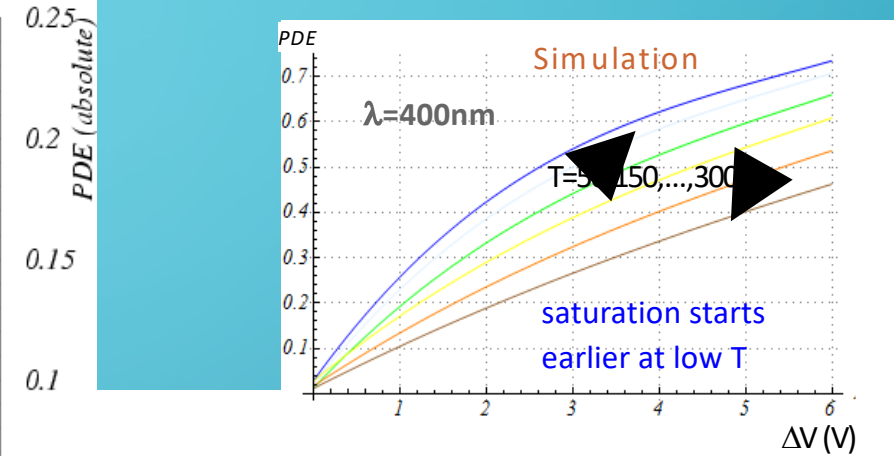


SPECTRAL SENSITIVITY

PDE vs λ (ΔV constant)



PDE ΔV vs (λ constant)



TIMING AT LOW TEMPERATURE

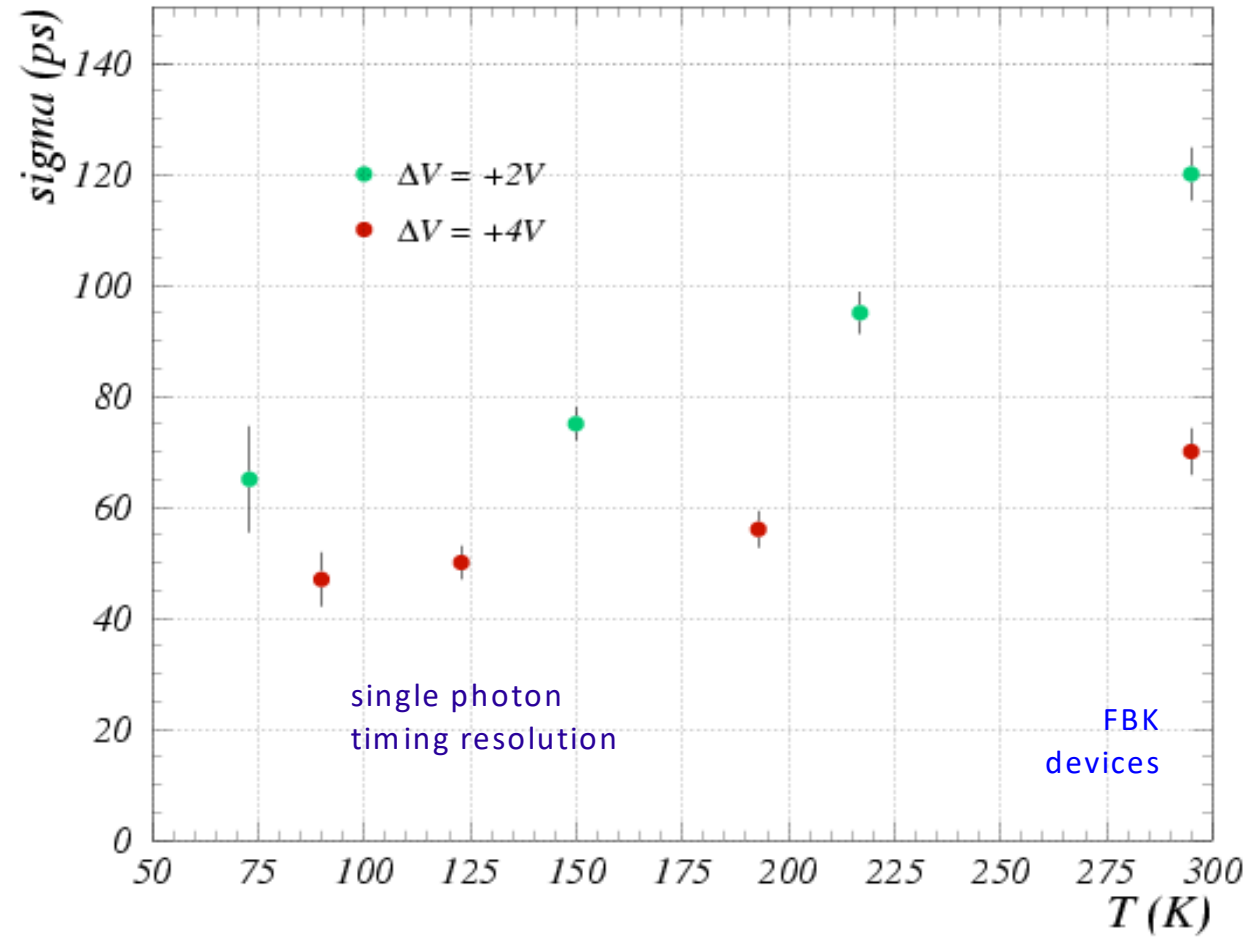
- Timing resolution improves with decreasing T
- Lower jitter at low T due to higher mobility:

a) avalanche process is faster

b) reduced fluctuations

NOTE:

- Ultimate timing resolution not likely to be a major factor for LXe/LAr experiments



G.C. (2011, unpublished)

SUMMARY

- Area of intensive research. Large body of results (very selected examples shown for the illustration) confirming the 'standard model' of SiPMs (no physics beyond the standard model, yet)
- Useful guide for the developments of specialized SIPMs (large area/low noise, VUV,..)
- Useful guide for development of testing and characterization techniques and strategies. For example: different physics processes dominate at different temperatures hence some of the characteristics measured at cryogenic temperatures may not be well correlated with the same characteristics measured at room temperatures → need for dedicated cryogenic testing setups.